



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Frank Y. Xu et al.
App. No.: 10/789,319 GPAU: 1712
Filing Date: 02/27/2004 Examiner: Marc S. Zimmer
Dkt. No.: P121-63-03 Conf. No.: 9202
For: COMPOSITION FOR AN ETCHING MASK COMPRISING A SILICON-
CONTAINING MATERIAL

INFORMATION DISCLOSURE STATEMENT

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- ☒ Form(s) PTO/SB/08A and/or PTO/SB/08B or PTO/1449
☐ Other:

to the Examiner's attention in the above-identified application. It is respectfully requested that the cited information be expressly considered during the prosecution of this application, and the references be made of record therein and appear among the "references cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed: before the mailing date of a first Office action on the merits or before the mailing date of a first Office action after the filing of a request for continued examination under § 1.114. Therefore, no fee is believed required.

Applicant(s) does not believe that any additional fees are due, but if the Commissioner believes additional fees are due,

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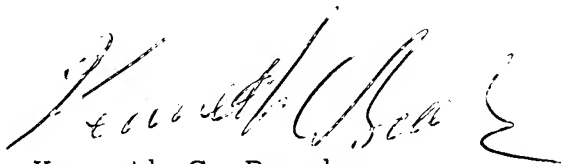
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1/5/09

Respectfully Submitted,



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PTO/SB/03A (03-03)

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Sheet

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of

25

Complete if Known

Application Number	10/789,319
Filing Date	02/27/2004
First Named Inventor	Xu et al.
Group Art Unit	1712
Examiner Name	Zimmer, Marc S.
Attorney Docket Number	P121-63-03

U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (if known)			
	A1	3,527,062		Belinski et al.	09-08-1970	
	A2	3,783,520		King	01-08-1974	
	A3	3,807,027		Heisler	04-30-1974	
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	A5	3,811,665		Seelig	05-21-1974	
	A6	4,062,600		Wyse	12-13-1977	
	A7	4,070,116		Frosch et al.	01-24-1978	
	A8	4,098,001		Watson	07-04-1978	
	A9	4,119,688		Hiraoka	10-10-1978	
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	A14	4,326,805		Feldman et al.	04-27-1982	
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	A22	4,544,572		Sandvig et al.	10-01-1985	
	A23	4,552,832		Blume et al.	11-12-1985	
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	A29	4,694,703		Routson	09-22-1987	
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	A31	4,724,222		Feldman	02-09-1988	
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	A33	4,737,425		Lin et al.	04-12-1988	
	A34	4,763,886		Takei	08-16-1988	
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			Examiner Name	Zimmer, Marc S.	
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		Number	Kind Code ² (if known)			
	A35	4,772,878		Kane	09-20-1988	
	A36	4,808,511		Holmes.	02-28-1989	
	A37	4,826,943		Ito et al.	05-02-1989	
	A38	4,846,931		Gmitter et al.	07-11-1989	
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	A41	4,857,477		Kanamori	08-15-1989	
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	A43	4,887,283		Hosno	12-12-1989	
	A44	4,891,303		Garza et al.	01-02-1990	
	A45	4,908,298		Hefferon et al.	03-13-1990	
	A46	4,909,151		Fukui et al.	03-20-1990	
	A47	4,919,748		Bredbenner et al.	04-24-1990	
	A48	4,921,778		Thackeray et al.	05-01-1990	
	A49	4,929,083		Brunner	05-29-1990	
	A50	4,931,351		McColgin et al.	06-05-1990	
	A51	4,959,252		Bonnebat et al.	09-25-1990	
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	A54	4,976,818		Hashimoto et al.	12-11-1990	
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	A64	5,110,514		Soane	05-05-1992	
	A65	5,126,006		Cronin et al.	06-30-1992	
	A66	5,148,036		Matsugu et al.	09-15-1992	
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Examiner Signature					Date Considered	

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		Number	Kind Code ² (if known)			
	A69	5,155,749		DiMilia et al.	10-13-1992	
	A70	5,169,494		Hashimoto et al.	12-08-1992	
	A71	5,171,490		Fudin	12-15-1992	
	A72	5,173,393		Sezi et al.	12-22-1992	
	A73	5,179,863		Uchida et al.	01-19-1993	
	A74	5,198,326		Hashimoto et al.	03-30-1993	
	A75	5,204,739		Domenicali	04-20-1993	
	A76	5,206,983		Guckel et al.	05-04-1993	
	A77	5,212,147		Sheats	05-18-1993	
	A78	5,218,193		Miyatake	06-08-1993	
	A79	5,234,793		Sebald et al.	08-10-1993	
	A80	5,240,550		Boehnke et al.	08-31-1993	
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	A82	5,242,711		DeNatale et al.	09-07-1993	
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	A85	5,270,984		Mine	12-14-1993	
	A86	5,277,749		Griffith et al.	01-11-1994	
	A87	5,314,772		Kozicki et al.	05-24-1994	
	A88	5,318,870		Hartney	06-07-1994	
	A89	5,324,683		Fitch et al.	06-28-1994	
	A90	5,328,810		Lowrey et al.	07-12-1994	
	A91	5,330,881		Sidman et al.	07-19-1994	
	A92	5,348,616		Hartman et al.	09-20-1994	
	A93	5,355,219		Araki et al.	10-11-1994	
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	A98	5,376,810		Hoenk et al.	12-27-1994	
	A99	5,380,474		Rye et al.	01-10-1995	
	A100	5,392,123		Marcus et al.	02-21-1995	
	A101	5,414,514		Smith et al.	05-09-1995	
	A102	5,417,802		Obeng	05-23-1995	
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		Number	Kind Code ² (if known)			
	A103	5,421,981		Leader et al.	06-06-1995	
	A104	5,422,295		CHOI et al.	06-06-1995	
	A105	5,424,549		Feldman	06-13-1995	
	A106	5,425,848		Haisma et al.	06-20-1995	
	A107	5,425,964		Southwell et al.	06-20-1995	
	A108	5,431,777		Austin	07-11-1995	
	A109	5,439,766		Day et al.	08-08-1995	
	A110	5,452,090		Proglar et al.	09-19-1995	
	A111	5,453,157		Jeng	09-26-1995	
	A112	5,458,520		DeMercurio et al.	10-17-1995	
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	A114	5,480,047		Tanigawa et al.	01-02-1996	
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	A116	5,507,411		Peckels	04-16-1996	
	A117	5,508,527		Kuroda et al.	04-16-1996	
	A118	5,512,131		Kumar et al.	04-30-1996	
	A119	5,515,167		Ledger et al.	05-07-1996	
	A120	5,523,878		Wallace et al.	06-04-1996	
	A121	5,527,662		Hashimoto et al.	06-18-1996	
	A122	5,545,367		Bae et al.	08-13-1996	
	A123	5,563,702		Emery et al.	10-08-1996	
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	A128	5,670,415		Rust	09-23-1997	
	A129	5,700,626		Lee et al.	12-23-1997	
	A130	5,723,176		Keyworth et al.	03-03-1998	
	A131	5,724,145		Kondo et al.	03-03-1998	
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	A135	5,736,424		Prybyla et al.	04-07-1998	
	A136	5,743,998		Park	04-28-1998	
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	A137	5,747,102		Smith et al.	05-05-1998	
	A138	5,753,014		Van Rijn	05-19-1998	
	A139	5,760,500		Kondo et al.	06-02-1998	
	A140	5,772,905		Chou	06-30-1998	
	A141	5,776,748		Singhvi et al.	07-07-1998	
	A142	5,779,799		Davis	07-14-1998	
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	A157	5,912,049		Shirley	06-15-1999	
	A158	5,926,690		Toprac et al.	07-20-1999	
	A159	5,937,758		Maracas et al.	08-17-1999	
	A160	5,942,871		Lee	08-24-1999	
	A161	5,948,219		Rohner	09-07-1999	
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	A165	5,988,859		Kirk	11-23-1999	
	A166	6,033,977		Gutsche et al.	03-07-2000	
	A167	6,035,805		Rust	03-14-2000	
	A168	6,036,055		Mogadam et al.	03-14-2000	
	A169	6,038,280		Rossiger et al.	03-14-2000	
	A170	6,039,897		Lochhead et al.	03-21-2000	
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	A171	6,046,056		Parce et al.	04-04-2000	
	A172	6,051,345		Huang	04-18-2000	
	A173	6,074,827		Nelson et al.	06-13-2000	
	A174	6,081,334		Brimbergen et al.	06-27-2000	
	A175	6,088,103		Everett et al.	07-11-2000	
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				Application Number	10/789,319
				Filing Date	02/27/2004
				First Named Inventor	Xu et al.
				Group Art Unit	1712
				Examiner Name	Zimmer, Marc S.
Sheet	7	of	25	Attorney Docket Number	P121-63-03

U.S. PATENT DOCUMENTS						
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Filing Date	02/27/2004
First Named Inventor	Xu et al.
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Examiner Name	Zimmer, Marc S.
Attorney Docket Number	P121-63-03

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			Filing Date	02/27/2004	
			First Named Inventor	Xu et al.	
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			Examiner Name	Zimmer, Marc S.	
			Attorney Docket Number	P121-63-03	
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				Examiner Name	Zimmer, Marc S.
				Attorney Docket Number	P121-63-03
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		Office ³	Number ⁴	Kind Code ⁵ (if known)				
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				First Named Inventor	Xu et al.
				Group Art Unit	1712
				Examiner Name	Zimmer, Marc S.
Sheet	14	of	25	Attorney Docket Number	P121-63-03

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	A378	BENDER et al., "Multiple Imprinting in UV-based Nanoimprint Lithography: Related Material Issues.", Microelectronic Engineering 61 – 62, January 1, 2002, pp. 407-413.	
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	A385	CHOU et al., "Imprint of Sub-25 nm Vias and Trenches in Polymers.", Applied Physics Letter, November 20, 1995, 67 (21)	
	A386	CHOU et al., "Lithographically Induced Self-assembly of Periodic Polymer Micropillar Arrays.", J. Vac. Sci. Technol., November 1, 1999, B 17(6), pp. 3197-3202.	
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	A398	GOKAN et al., "Dry Etch Resistance of Organic Materials.", J. Electrochem. Soc.: SOLID-STATE SCIENCE AND TECHNOLOGY, January 1, 1983, pp. 143-146.	
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	A407	HIRAI et al., "Mold Surface Treatment for Imprint Lithography.", Journal of Photopolymer Science and Technology, August 1, 2001, Vol. 14, No. 3, pp. 457-462.	
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	A410	HOLLIS et al., "A Six-Degree-of-Freedom Magnetically Levitated Variable Compliance Fine-Motion Wrist: Design, Modeling, and Control.", IEEE Transactions on Robotics and Automation, June 1, 1991, Vol 7., No. 3, pp. 320 - 332.	

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	A422	KOSEKI, "Design and Accuracy Evaluation of High-Speed and High Precision Parallel Mechanism.", Proc. Of IEEE, January 1, 1998, Intl. Conf. on Robotics & Automation, pp. 1340-1345.	
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	A434	MERLET, "Parallel Manipulators: State of the Art and Perspectives.", Advanced Robotics, January 1, 1994, Vol. 8, pp. 589-596.	
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				Filing Date	02/27/2004
				First Named Inventor	Xu et al.
				Group Art Unit	1712
				Examiner Name	Zimmer, Marc S.
Sheet	22	of	25	Attorney Docket Number	P121-63-03

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	A466	SAGIV, "Organized Monolayers by Absorption. 1. Formation and Structure of Oleophobic Mixed Monolayers on Solid Surfaces.", Journal of American Chemical Society/102:1, January 2, 1980.	
	A467	SCHEER et al., "Problems of the Nanoimprinting Technique for Nanometer Scale Pattern Definition.", J. Vac. Sci. Techno. B., November 1, 1998, pp. 3917-3921.	
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	A469	SLOCUM, "Precision Machine Design: Macromachine Design Philosophy and Its Applicability to the Design of Micromachines.", Micro Electro Mechanical Systems, February 4, 1992.	
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	A472	SRINIVASAN et al., "Alkyltrichlorosilane-Based Self-Assembled Monolayer Films for Stiction Reduction in Silicon Micromachines.", Journal of Microelectromechanical Systems, June 1, 1998, Vol. 7, No. 2, p. 252-260.	
	A473	STEWART, "A Platform With Six Degrees of Freedom.", Proc Instn Mech Engrs, May 28, 1965, Vol 180, Pt1, No. 15, pp. 371-378.	
	A474	STIX, "Getting More from Moores", Scientific American	
	A475	SUNG et al., "Abstract of Micro/nano-tribological Characteristics of Self-Assembled Monolayer and its Application in Nano-Structure Fabrication", Elsevier Science B.V., July 1, 2003, Vol. 255, no. 7	
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	A477	TAJBAKSH et al., "Three-Degree-of-Freedom Optic Mount for Extreme Ultraviolet.", American Society for Precision Engineering, January 1, 1998, pp. 359-362.	
	A478	TANIKAWA et al., "Development of Small-sized 3 DOF Finger Module in Micro Hand for Micro Manipulation.", Proc. of IEEE, March 1, 1999, Intl. conf. on Intelligent Robots and Systems, pp. 876-881.	
	A479	TOMITA et al., "A 6-axes Motion Control Method for Parallel-Linkage-Type Fine Motion Stage.", JSPE-58-04, pp. 118-124.	
	A480	Translation of Japanese Patent 02-24848, January 26, 1990.	
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	A482	TRILOGY SYSTEMS, "Linear Motors 310.", www.trilogysystems.com, January 1, 2001.	
	A483	UCHIDA et al., "A Mask-to-Wafer Alignment and Gap Setting Method for X-ray Lithography Using Graftings.", Journal Vacuum Science Technology, November 1, 1991, B 9 (6), pp. 3202-3206.	
	A484	US Application No. 09/698,317, Filed 10-27-2000, CHOI et al., "High Precision Orientation Alignment and Gap Control Stages for Imprint Lithography Processes."	
	A485	US Application No. 10/463,396, Filed 06-17-2003, CHOI et al., "Method to Reduce Adhesion Between a Conformable Region and a Pattern of a Mold."	
	A486	US Application No. 10/614,716, Filed 07-07-2003, SREENIVASAN et al., "A Conforming Template for Patterning Liquids Disposed on Substrates."	
	A487	US Application No. 10/666,527, Filed 09-18-03, BAILEY et al., "Imprint Lithography Templates having Alignment Marks."	

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	A488	US Application No. 10/677,639, Filed 10-02-03, MCMACKIN et al., "Single Phase Fluid Imprint Lithography Method."	
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	A494	US Application No. 10/785,248, Filed 02-24-2004, CHOI et al., "A Method to Control the Relative Position Between a Body and a Surface."	
	A495	US Application No. 10/788,700, Filed 02-27-2004, SREENIVASAN et al., "Full-Wafer or Large Area Imprinting with Multiple Separated Sub-Fields for High Throughput Lithography."	
	A496	US Application No. 10/864,214, Filed 6-9-04, SREENIVASAN et al., "An Imprint Lithography System to Produce a Light to Impinge upon and Polymerize a Liquid in Superimposition with Template Overlay Marks."	
	A497	US Application No. 10/898,034 Filed 07-23-04, MCMACKIN et al., "A Method of Creating a Turbulent Flow of Fluid between a Mold and a Substrate."	
	A498	US Application No. 10/898/037, Filed 07-23-04, MCMACKIN et al., "A System of Creating a Turbulent Flow of Fluid between a Mold and a Substrate."	

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	A499	US Application No. 60/394,458, Filed 07-08-2002, SREENIVASAN et al., "Method and Apparatus for Whole Wafer Planarization using Optical Flats and Light Curable Liquids."	
	A500	US Applications No. 10/616,294, Filed 07-09-2003, CHOI et al., "Systems for Magnification and Distortion Correction for Imprint Lithography Processes."	
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	A502	WANG et al., "Passive Compliance versus Active Compliance in Robot-Based Automated Assembly Systems.", Industrial Robot, January 1, 1998, Vol. 25, No. 1, pp. 48-57.	
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